



PATENT

46379

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Takashi FUJII et al.

Serial No.: 10/784,211

Filed: February 24, 2004

For: PROCESS FOR PRODUCING COLD
FIELD EMISSION CATHODES

Group Art Unit: 1734

Examiner: J. Sells

RESPONSE AFTER FINAL

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This is in response to the January 27, 2006 Office Action.

In the Action, claims 1-34 are rejected. In view of the following comments,
reconsideration and allowance are requested.

Rejection of Claims 1-34

Claims 1-34 are rejected under 35 U.S.C. § 103(a) as being obvious over U.S. Patent No. 6,097,138 to Nakamoto in view of U.S. Patent No. 6,436,221 to Chang et al. Nakamoto is cited for disclosing a field emission cold cathode device by forming nanotubes on a substrate and then applying a conductive material over the nanotubes and the substrate. Chang et al. is cited as allegedly disclosing a taping method to remove a portion of the carbon nanotubes from a substrate. The rejection is based on the position that it would have been obvious to modify the process of Nakamoto according to Chang et al. to include a taping

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